



**UNIVERSITI TEKNOLOGI MARA**

**INVESTIGATION ON BREAKDOWN VOLTAGE OF  
TiO<sub>2</sub> DOPED AL<sub>2</sub>O<sub>3</sub> VIA SPIN COATING METHOD**

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## ABSTRACT

Thin films of TiO<sub>2</sub> doped Al<sub>2</sub>O<sub>3</sub> were prepared by spin coating method on glass substrate. The main objectives of this project are to prepare the TiO<sub>2</sub> doped Al<sub>2</sub>O<sub>3</sub> thin films for measuring the breakdown voltage and to characterize the electrical, physical and optical properties TiO<sub>2</sub> doped Al<sub>2</sub>O<sub>3</sub> of thin films. Characterization of the thin films were carried out using different characterization techniques such as X-Ray diffraction (XRD), breakdown voltage and UV-Vis. Different percentages of Aluminum Oxide (Al<sub>2</sub>O<sub>3</sub>) in TiO<sub>2</sub> were 0at%, 2at%, 4at%, 6at%, 8at% and 10at%. The thin films were annealed at 450°. The results show the breakdown voltage increased as the percentage of the atomic of Al<sub>2</sub>O<sub>3</sub> increased. The XRD analysis of the thin films showed amorphous behaviors. The anatase phase transformation of TiO<sub>2</sub> was formed as the thin films annealed at 450°. Further analysis on UV-Vis also has found that the percentage of transmittance of TiO<sub>2</sub> doped Al<sub>2</sub>O<sub>3</sub> increased as the percentage of atomic of Al<sub>2</sub>O<sub>3</sub> increased. In contrast to the transmittance spectrum, the percentage of absorbance of TiO<sub>2</sub> doped Al<sub>2</sub>O<sub>3</sub> was found to be decreasing with increasing of the percentage of atomic of Al<sub>2</sub>O<sub>3</sub>.

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# CHAPTER 1

## INTRODUCTION

### 1.1 BACKGROUND OF STUDY

Titanium dioxide ( $\text{TiO}_2$ ) thin films have received a great deal of interest due to an important number of applications such as electrochromic, photovoltaic and microelectronic devices. Its electron transport properties remain back due to its high resistivity. Although many structural and optical studies were carried out for  $\text{TiO}_2$ , the impurity band conduction may become significant even above room temperature due to  $\text{TiO}_2$  semiconductor thin films having a high energy gap. Electrical conductivity processes are mainly due hopping via impurity centers, while the contribution of intrinsic free carriers is negligible even at high temperatures. The measured conductivity of  $\text{TiO}_2$  thin films is generally explained in terms of the simple thermally activated conduction at high temperatures (  $T > 300 \text{ K}$  ).

Doping is a reversible process which could be carried out chemically or electrochemically with oxidation or reduction by accepting or donating the electrons respectively and thus results to the positive or negative charges. By adding the dopants such as Nb, Cr, Sn, Pt, Zn, Al, La and Y, it has been showed that the sensitivity of  $\text{TiO}_2$  can be improved.  $\text{TiO}_2$  is well known that the impurity doping induces substantial modifications in electrical and optical properties of semiconductor materials. Increased in conductivity, slowing down anatase to rutile transformation and reducing grain growth are the most important effects of dopants addition in  $\text{TiO}_2$ . Recent studies has reported that the N-doping shift that absorption band associated with the band gap narrowing. The process